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Scaling Up Substrate for Coated Conductors at SuperPower, Inc.

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Objectives & Approaches

- **Objective: Scale up substrate fabrication to assist Coated Conductor processes to produce tape in piece-lengths greater than 1 km with uniform low surface roughness and good buffer texture**
- **Current Approaches: Reel-to-reel polishing, cleaning, IBAD buffer deposition**
- **Emphasis is on establishing**
 - **improved substrate manufacturing processes,**
 - **reel-to-reel on-line & off-line QC tools**
 - **equipment with increased yield for long length**

Issues affecting substrate quality

■ Surface roughness

- Rough raw material, inclusions and precipitates
- Mechanical grooves and grain boundaries
- Particles generated in IBAD chamber

■ Cleanliness

- Residual polishing media and organic residues

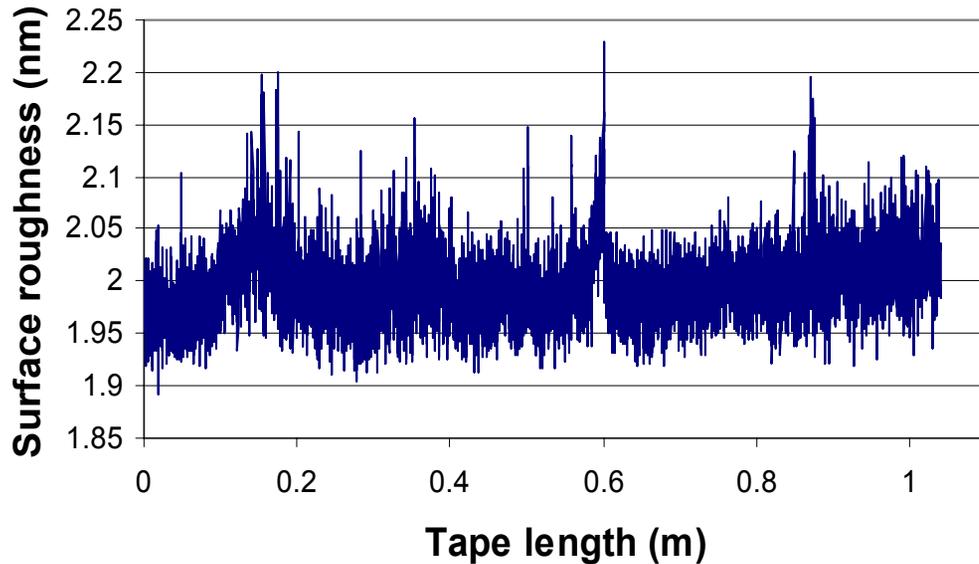
■ Adhesion

- delamination at interface of buffer layer and metal tape

■ Non-uniformity along tape length

- Roughness and IBAD texture
- Mechanical deformation and stress concentration

Highly smooth metal substrates are being produced in reel-to-reel polishing facility



Av. roughness over 1 m = **2 nm**

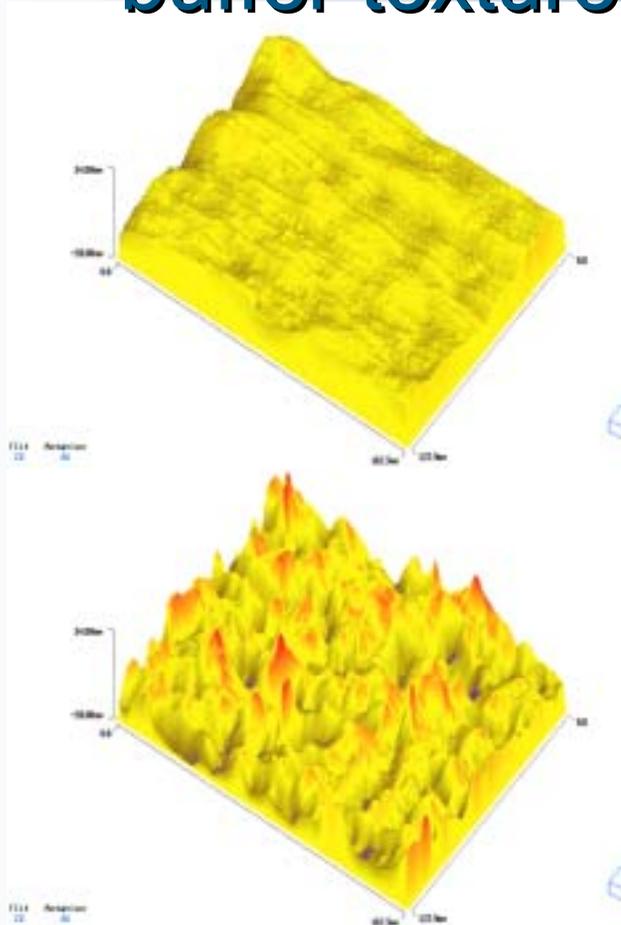
Std. deviation over 1 m =
0.033 nm (1.6%)



Tapes up to 100 m in single-piece lengths have been continuously polished.



Metal substrates surface roughness affect buffer texture and I_c of YBCO



$R_a = 20 \text{ \AA}$

Average Buffer Texture = 13.7°

$I_c = 100\text{A}$

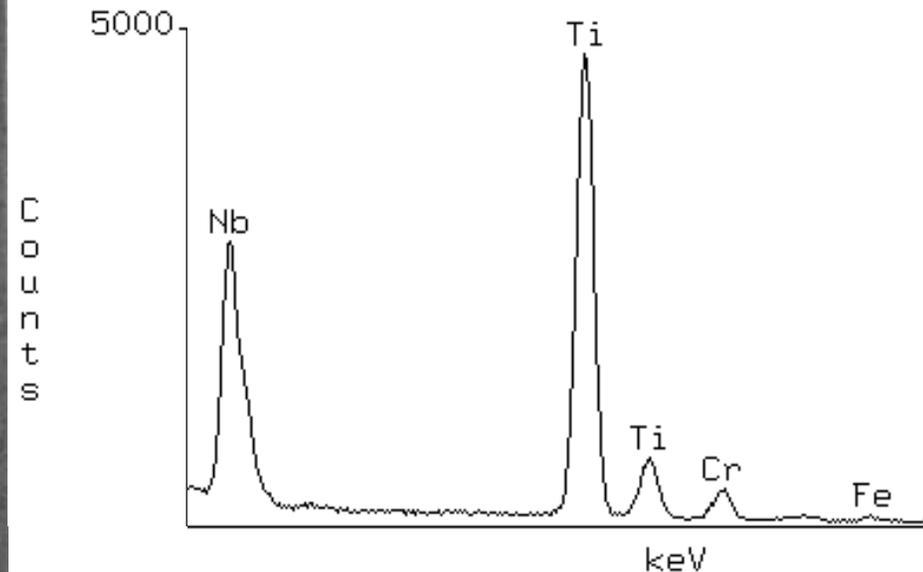
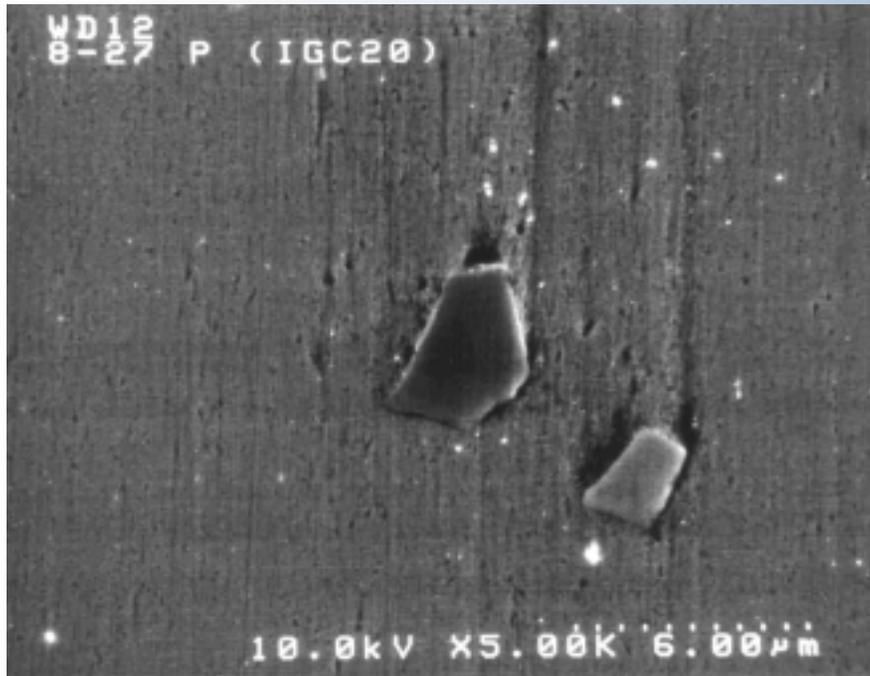
$R_a = 50 \text{ \AA}$

Average Buffer Texture = 15.4°

$I_c = 61\text{A}$

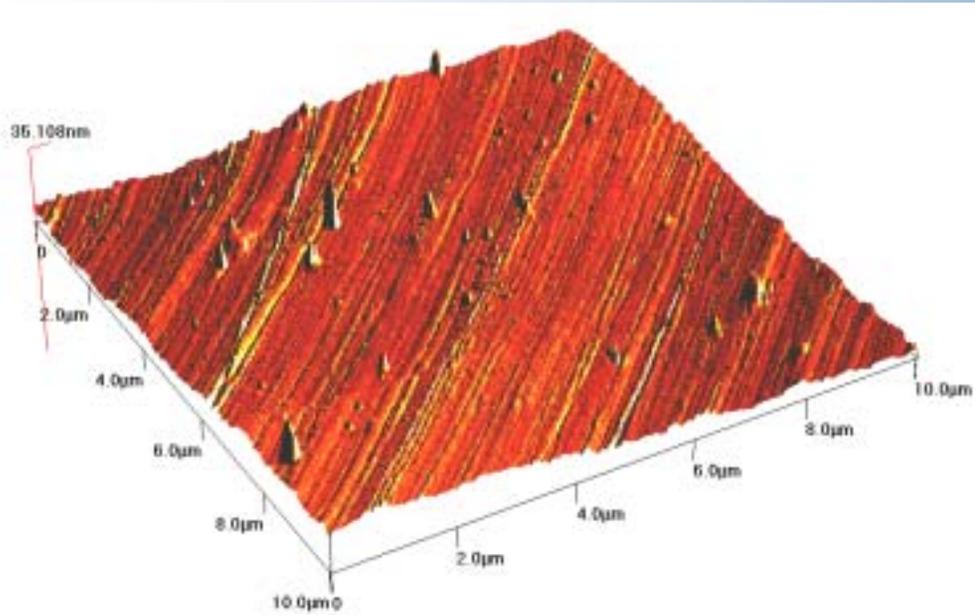
Buffer and YBCO process conditions are the same for the two sets of samples

Hard precipitates in raw material

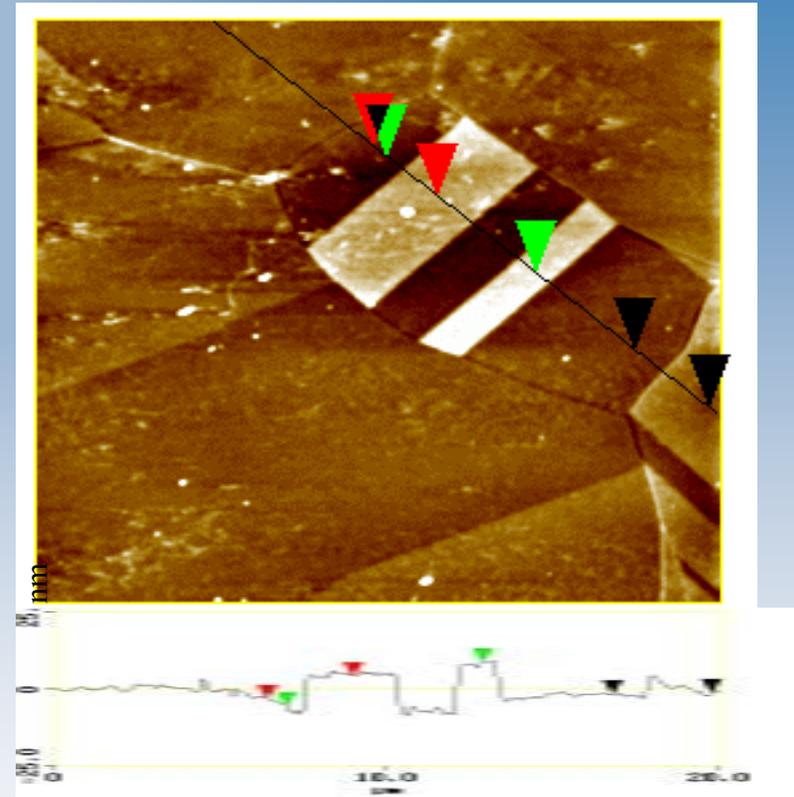


- **Hard Precipitates (Nb, Ti) in tape affect surface quality of polished substrate**

Grooves & Grain boundaries

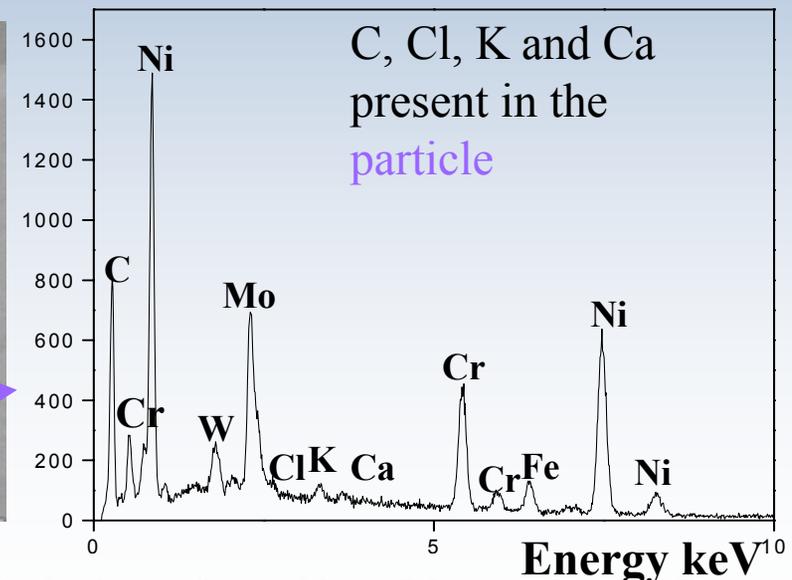
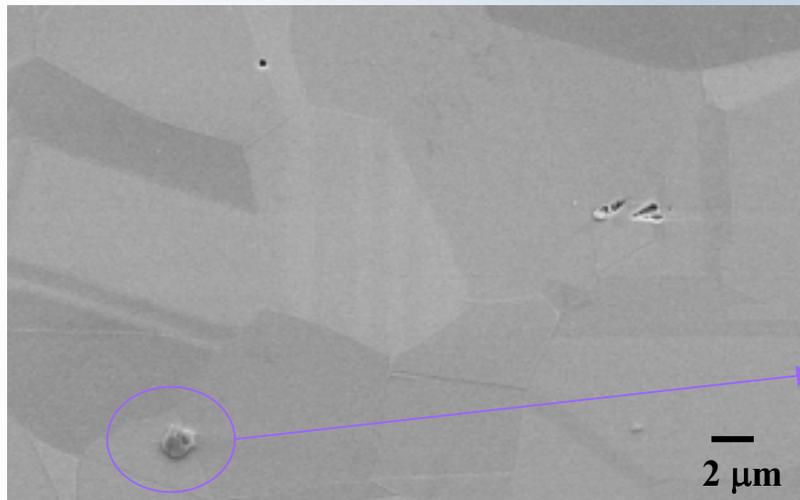
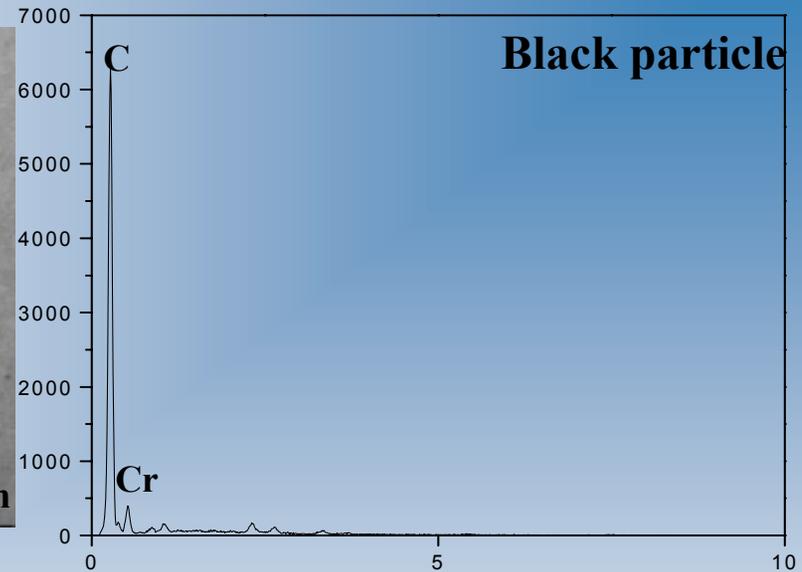
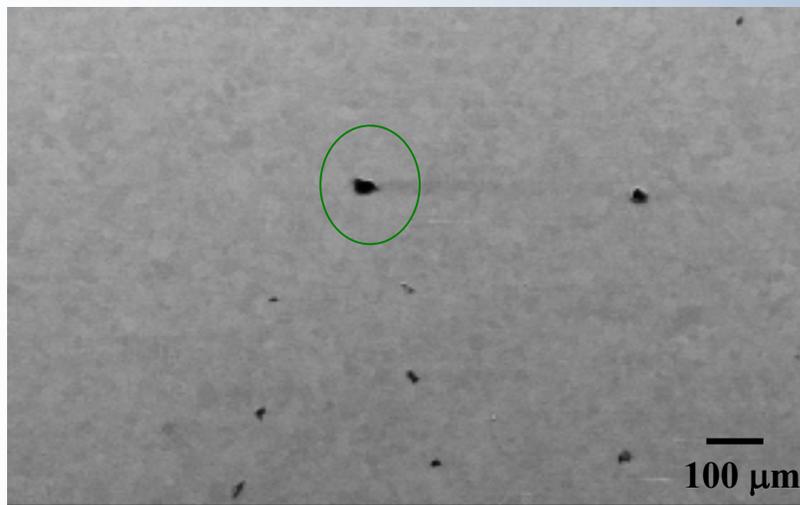


**Grooves are ~100nm wide
and 2-4nm deep**

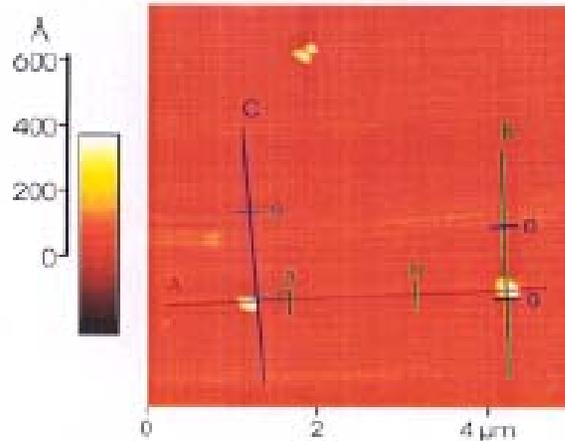


Vertical distance
 7.57nm (twin 1)
 14.3nm (twin 2)
 0.3nm (grain boundary)

Contamination on polished metal surface



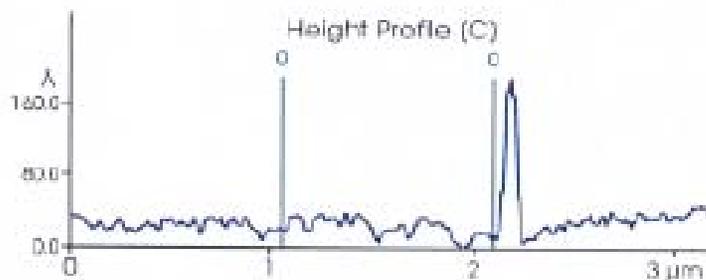
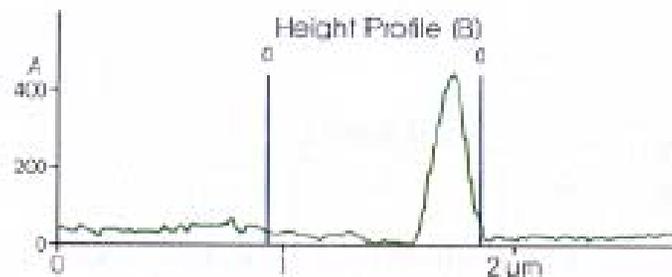
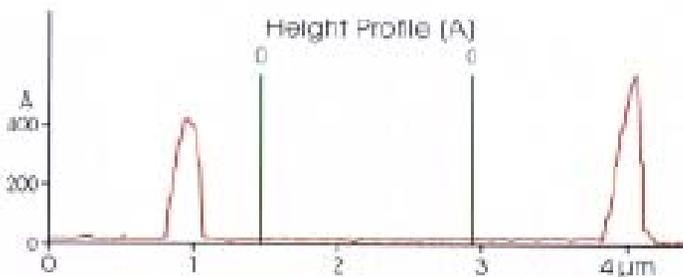
Substrate cleanliness is an issue



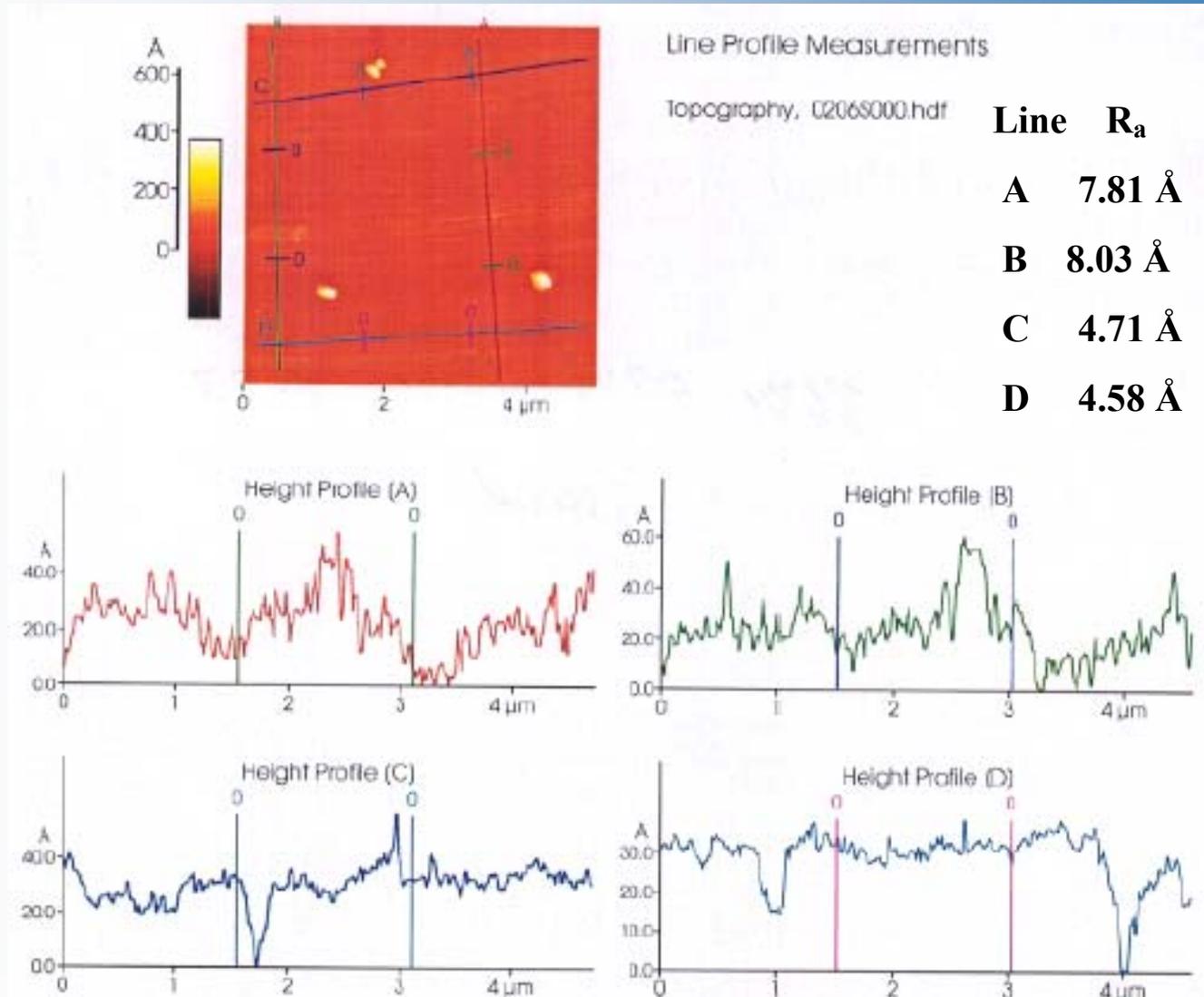
Line Profile Measurements

Topography: 02068000.hdf

Line	R_a
A	64.6 Å
B	41.2 Å
C	9.69 Å

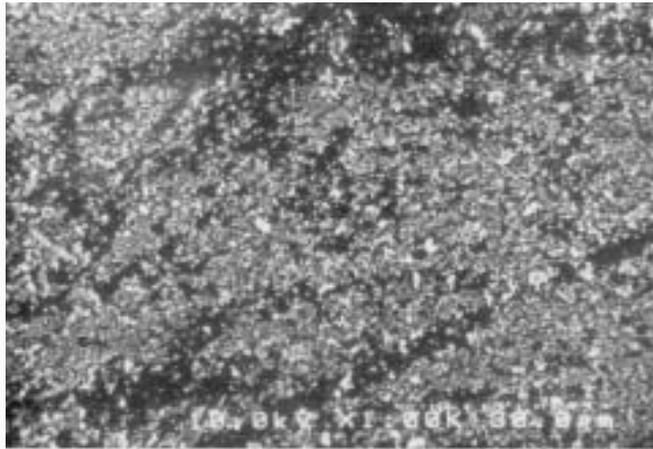


Effect of Residue on the Tape Roughness

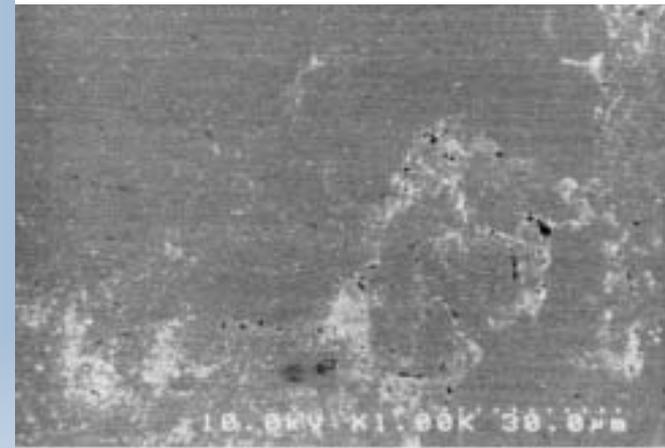


Substrate cleaning techniques developed to minimize surface contamination & defects

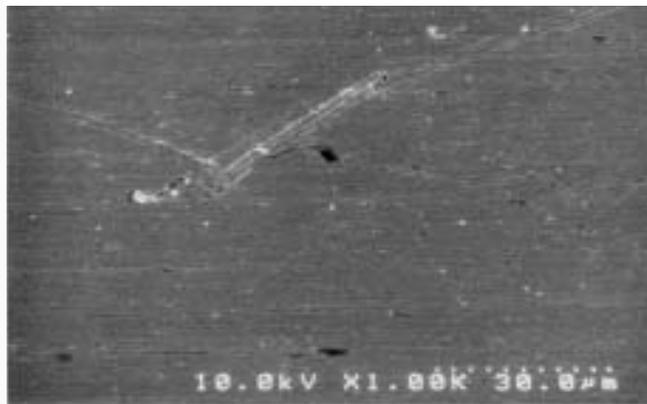
After Polishing



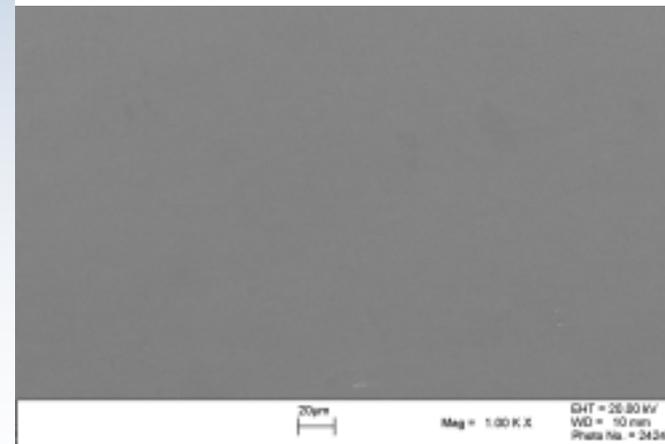
Ultrasonic Cleaning



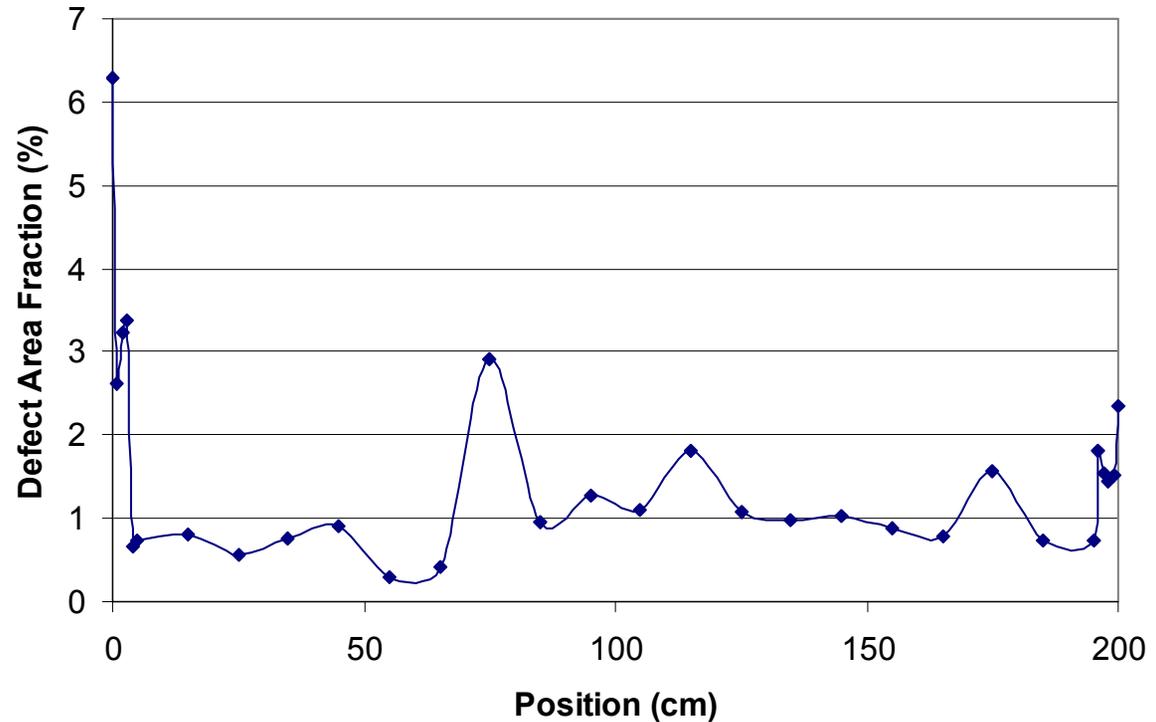
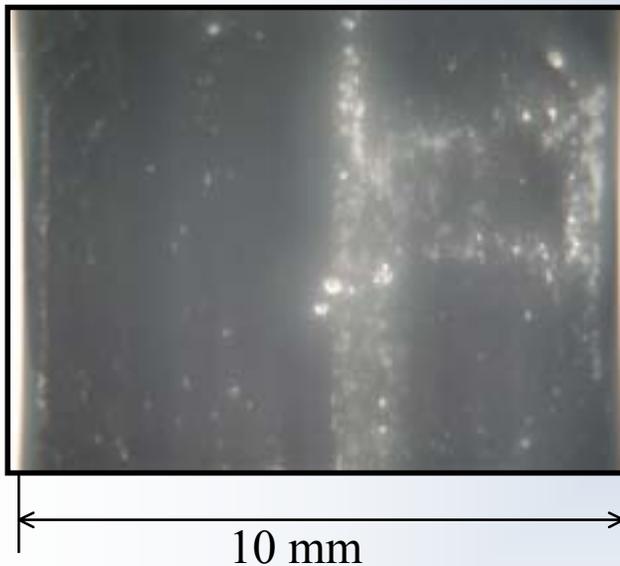
Chemical Cleaning



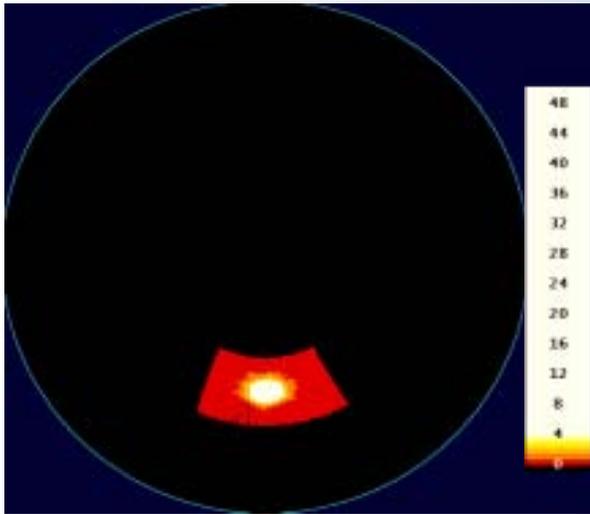
SuperPower Cleaning



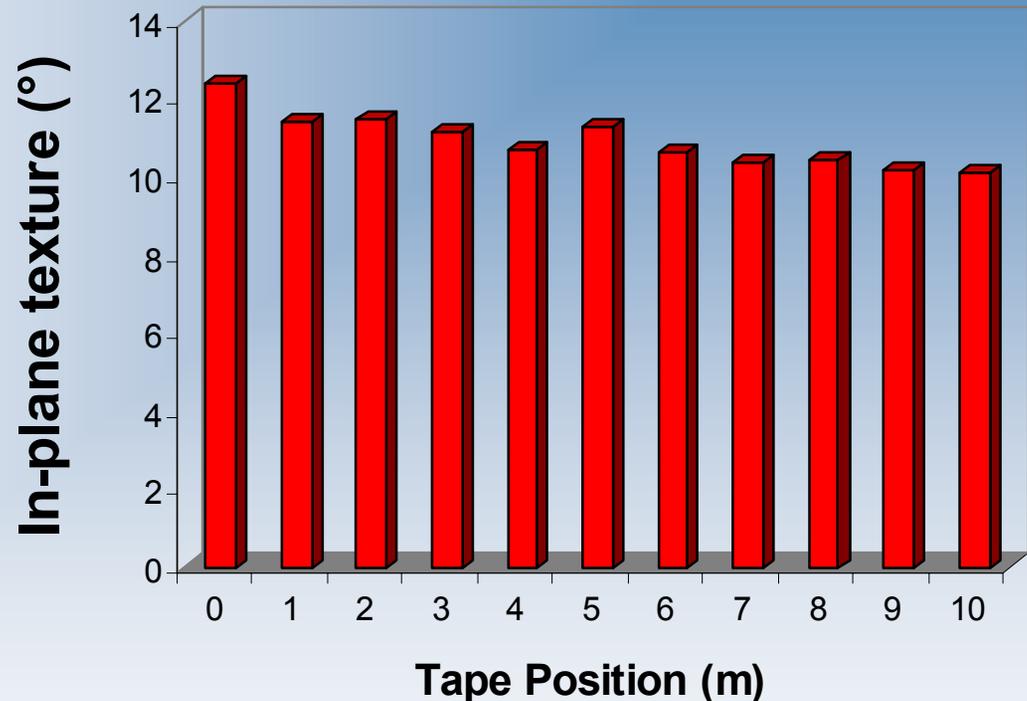
Quantitative defect analysis of meter-long tapes is routinely done



Uniform, well-textured 10 m IBAD tapes produced

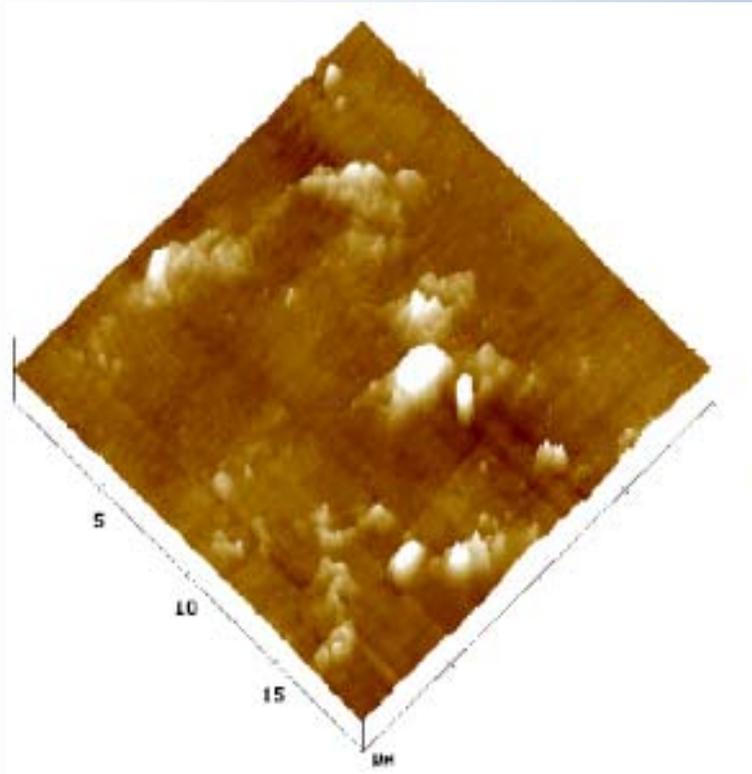


Direct in-plane texture measurement of long tapes using polefigures to calculate FWHM of (111) peaks

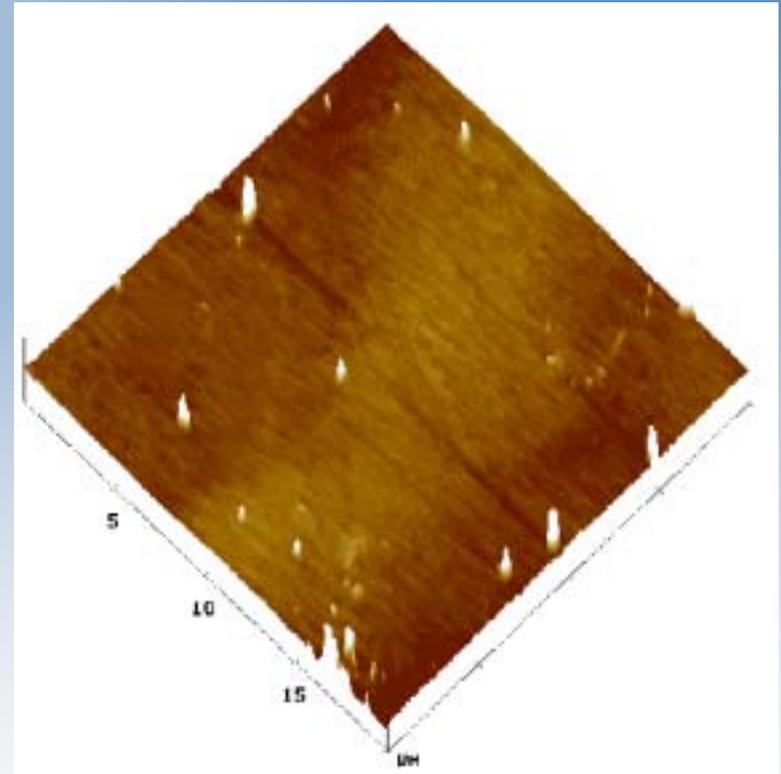


- **Average in-plane texture over 10 m = 10.9°**
- **Standard deviation = 0.7°**

Particulates found in buffer layers

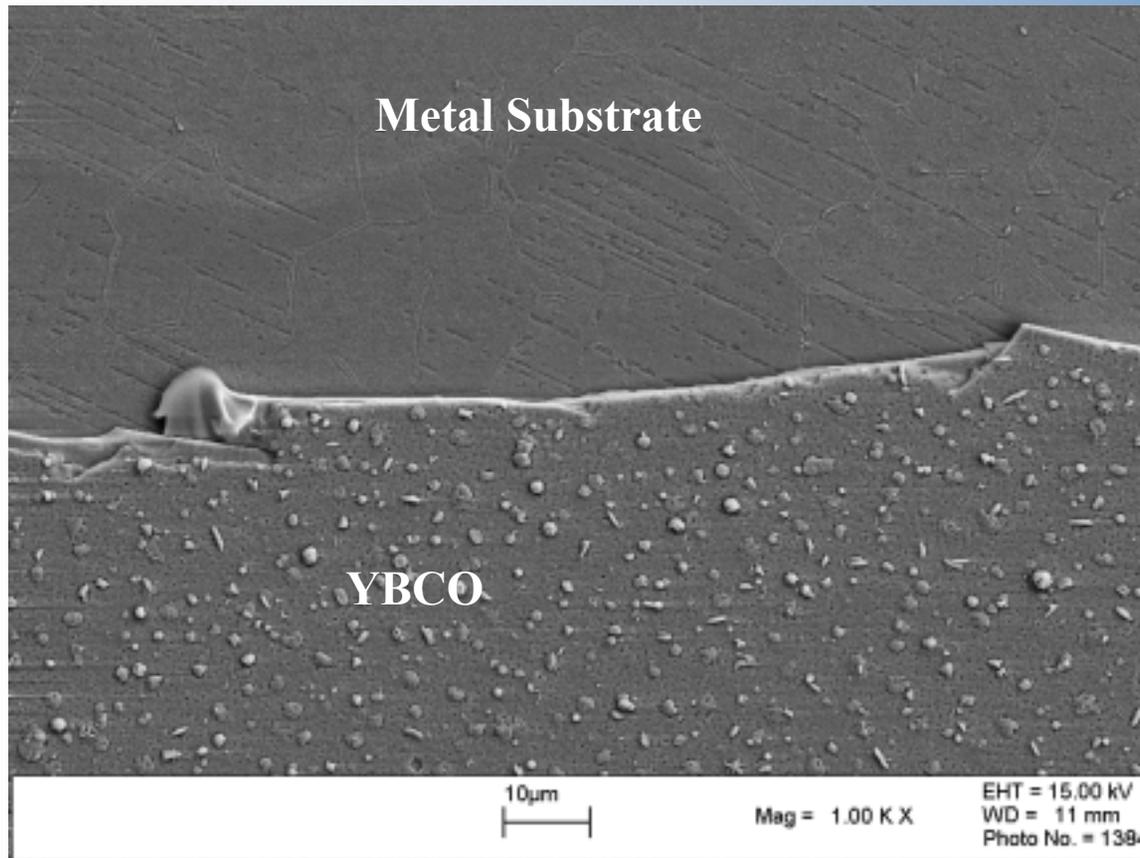


Average roughness = 12.7 nm



Average roughness = 4.6 nm

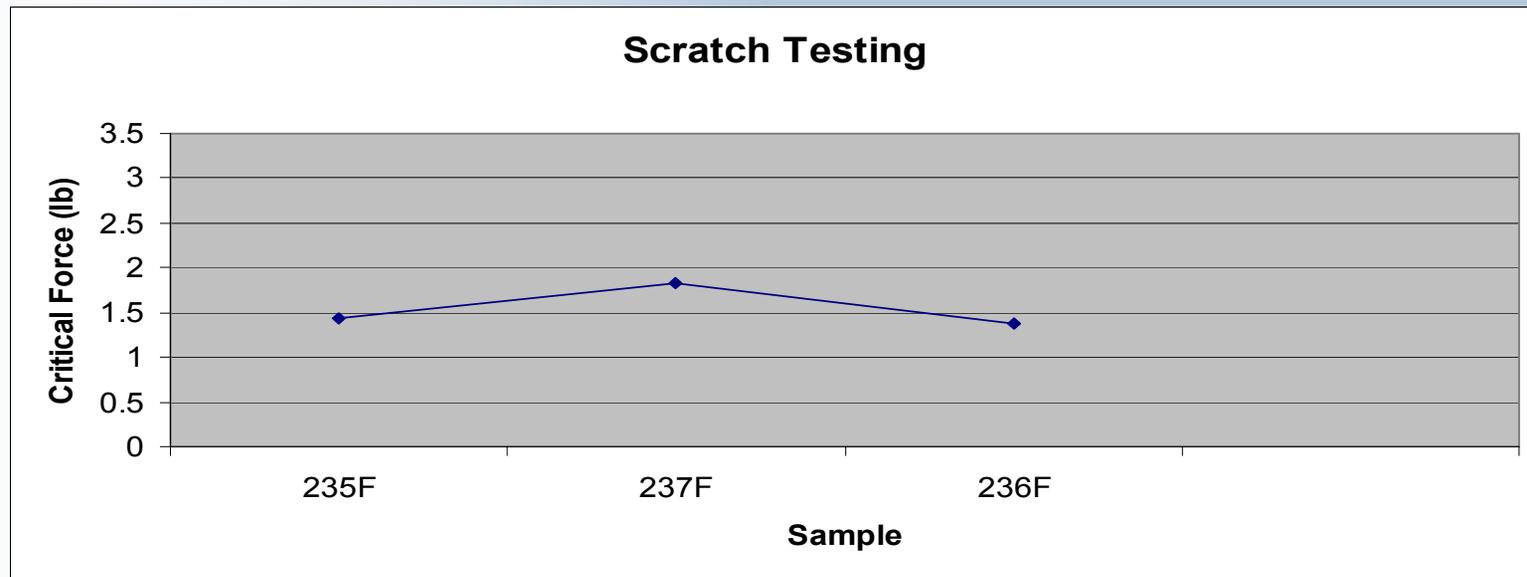
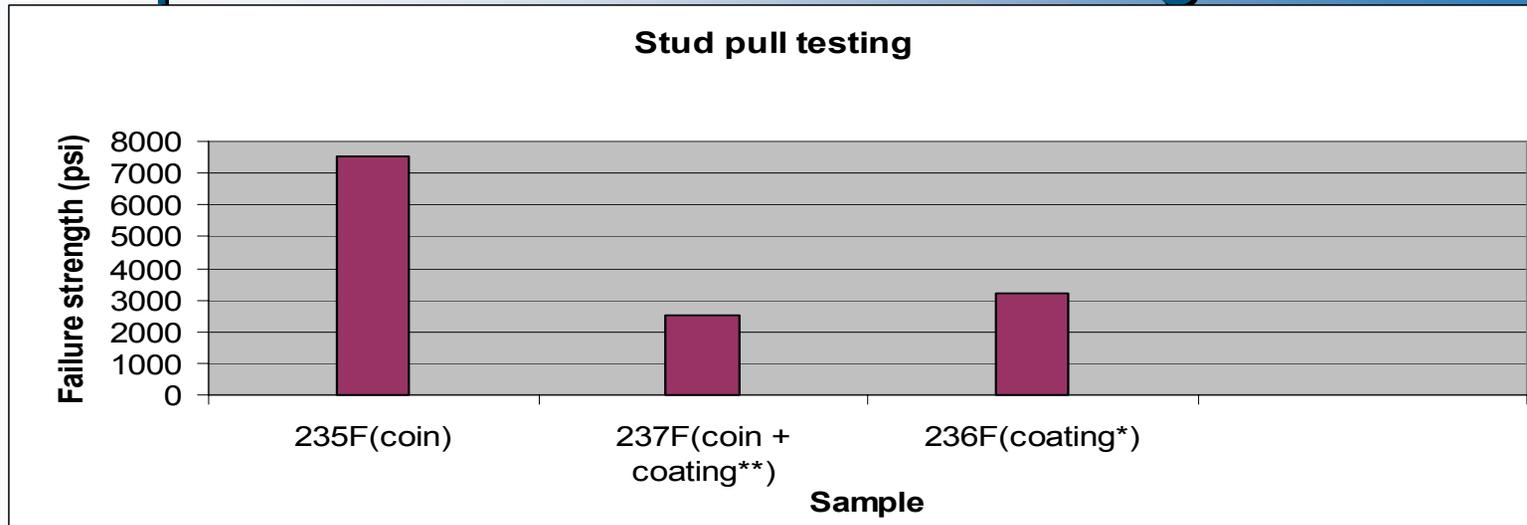
Delamination of buffer after YBCO deposition



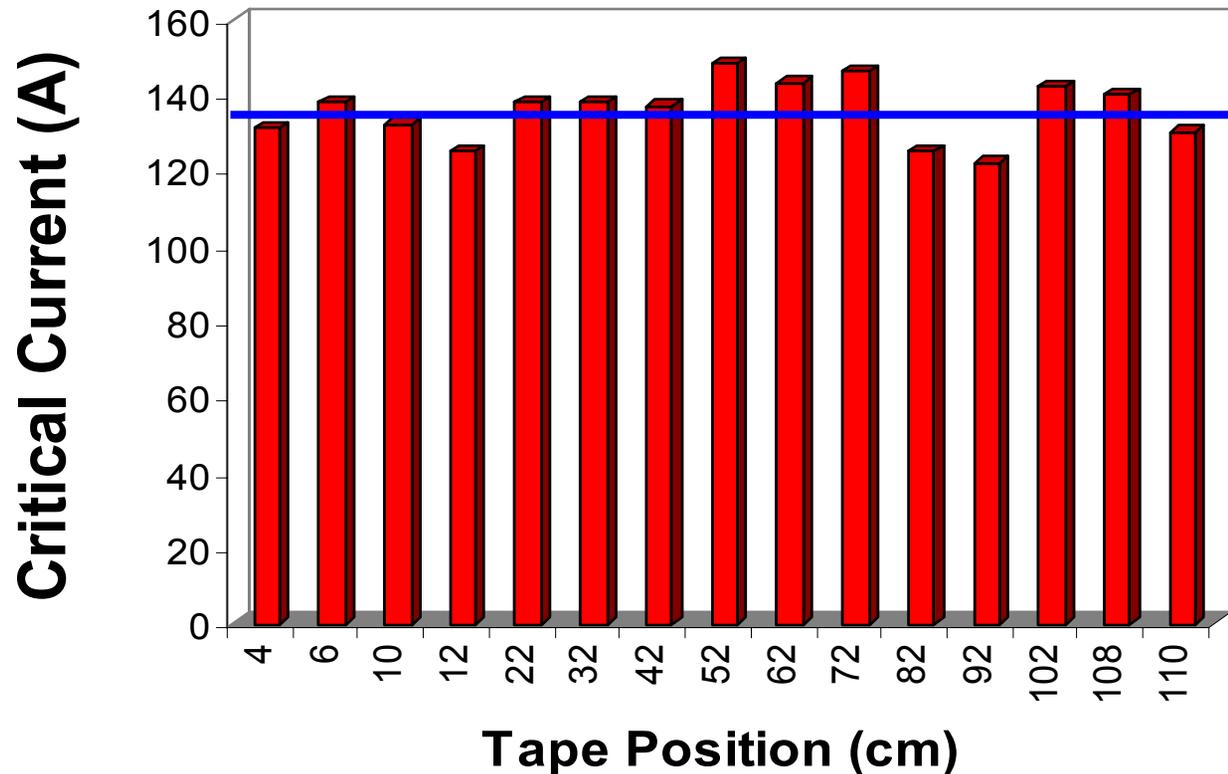
1 mm on each side
delaminated.
Effective I_c /cm width
= 127 A over 1 m

End-to-end I_c = 101 A over 1.24 m

Comparison of Adhesion Testing Methods



Elimination of delamination problem led to higher currents in meter-lengths



End-to-end $I_c = \underline{135 \text{ A over 1.1 m}}$